

## WHAT IS CLAIMED IS:

1. A substrate processing apparatus successively transporting a substrate between a plurality of processing parts thereby performing prescribed processing on said substrate, comprising:

a transport robot successively transporting said substrate between said plurality of processing parts along a prescribed procedure; and

a plurality of inspection parts, performing substrate inspections of different contents respectively, provided in said substrate processing apparatus.

2. The substrate processing apparatus according to claim 1, wherein said transport robot transports said substrate to selected inspection parts partially or totally selected from said plurality of inspection parts.

3. The substrate processing apparatus according to claim 2, wherein said transport robot successively transports a set of plural substrates along the same procedure so that said set of plural substrates are subjected to the same processing, and

said transport robot transports each of part or all of said set of plural substrates to a single said inspection part selected from said plurality of inspection parts thereby transporting at least one of said set of plural substrates to each of said plurality of inspection parts.

4. The substrate processing apparatus according to claim 3, wherein a transport path is formed along said procedure, and

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an inspection part performing a prescribed inspection on said substrate;

a transportation control part controlling said transport part to successively transport said substrate along said procedure set by said procedure setting part.

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11. The substrate processing apparatus according to claim 9, wherein  
said procedure setting part is capable of setting said procedure every set of a  
prescribed number of said substrates.

12. A substrate processing apparatus successively transporting a substrate between a plurality of processing parts thereby performing prescribed processing on said substrate, comprising:

a transport part successively transporting said substrate between said plurality of processing parts along a prescribed procedure;

a plurality of inspection parts performing prescribed inspections on said substrate;

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a procedure setting part capable of individually incorporating substrate transportation to said plurality of inspection parts into an arbitrary order position in said procedure; and

a transportation control part controlling said transport part to successively transport said substrate along said procedure set by said procedure setting part.

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13. The substrate processing apparatus according to claim 12, wherein each of said plurality of inspection parts is any of a thickness measuring part measuring the thickness of a resist film, a line width measuring part measuring the line width of a pattern, an overlay measuring part measuring overlay of said pattern and a  
15 macro defect inspection part.

14. The substrate processing apparatus according to claim 12, wherein any of said plurality of inspection parts is capable of performing resist film thickness measurement, pattern line width measurement and pattern overlay  
20 measurement.

15. The substrate processing apparatus according to claim 13, wherein said procedure setting part is capable of setting said procedure every substrate.

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16. The substrate processing apparatus according to claim 13, wherein

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a) a substrate processing apparatus comprising:

a-1) a plurality of processing parts processing said substrate,

a-2) a transport part successively transporting said substrate between said plurality of processing parts along a prescribed procedure, and

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a-3) an inspection part performing a prescribed inspection on said substrate;

b) a procedure setting part capable of incorporating substrate transportation to said inspection part into an arbitrary order position in said procedure; and

c) a transportation control part controlling said transport part to successively transport said substrate along said procedure set by said procedure setting part.

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18. The substrate processing system according to claim 17, wherein

said procedure setting part is capable of setting said procedure every said substrate.

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19. The substrate processing system according to claim 17, wherein

said procedure setting part is capable of setting a procedure every set of a prescribed number of said substrates.

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